

AMENDMENTS TO THE CLAIMS:

This listing of claims will replace all prior versions, and listings, of claims in the application:

LISTING OF CLAIMS:

1. (Currently Amended) A method ~~[[Method]]~~ of modifying a radio frequency (RF) response, comprising:

establishing an RF response in a signal path formed through plural segmented and cascaded conductive legs of a device; and

controlling an ~~[[actuator]]~~ actuator, which is formed by a post machining CMOS processing to be moveable, ~~[[and]]~~ to move at least one of the conductive legs thereby structurally ~~[[alter]]~~ altering the signal path and dynamically ~~[[change]]~~ changing an impedance of the signal path to alter the RF response.
2. (Currently Amended) ~~Method~~ The method according to claim 1, wherein modifying the RF response includes modifying at least one of the frequency, phase and amplitude of a signal received along the signal path.
3. (Currently Amended) ~~Method~~ The method according to claim 1, wherein the actuator is a microelectromechanical system device.
4. (Currently Amended) ~~Method~~ The method according to claim 1, wherein the device is at least one of a filter, a phase shifter and an attenuator.

5. (Currently Amended) ~~Method~~ The method according to claim 1, wherein the controlling to dynamically change an impedance occurs in response to an external excitation.

6. (Currently Amended) ~~Method~~ The method according to claim 1, comprising:
using undercut post CMOS processing to form the actuator, as a dynamically movable conductor.

7. (Currently Amended) An apparatus for modifying a radio frequency (RF) response comprising:
a signal path formed through plural segmented and cascaded conductive legs, the signal path having an RF transfer function; and
an actuator formed by a post machining CMOS processing to be moveable for tuning the device by structurally moving at least one of the conductive legs to change ~~[[changing]]~~ the signal path and to alter the RF transfer function.

8. (Currently Amended) ~~Apparatus~~ The apparatus according to claim 7, wherein the actuator is a microelectromechanical system device.

9. (Currently Amended) ~~Apparatus~~ The apparatus according to claim 7, wherein the signal path is a segmented path having cascaded legs, wherein coupling coefficients of the cascaded legs are altered using the actuator.

10. (Currently Amended) ~~Apparatus~~ The apparatus according to claim 8, wherein the microelectromechanical system is a post machined section of a CMOS circuit.